

The Conference Theme

“Electron Devices for Future Safe and Comfortable Society”

Table of Contents

5/13

Tutorials (in Japanese)

9:40-10:40 Growth and Device Applications of Zinc Oxide
S.Sasa, K. Koike, M. Yano, T. Maemoto, M. Inoue (Osaka Institute of Technology)

10:50-11:50 Low Power Technology for CMOS-LSI
H. Shinohara (STARC)

Opening

13:10-13:20 Opening Remarks by Y. Akasaka (Osaka University)

Keynote Speeches (I)

13:20-14:00

K-1 (p.16) Monitoring and Targeting of Cancer: Current status of Cancer Serum Test and Practical Hints for Next Generation Advancement of Technology
M. Tanaka (AIST)

14:00-14:40

K-2 (p.18) Electron Devices of IRT (Information and Robot Technology) in Aging Society
I. Shimoyama (University of Tokyo)

Break (14:40-14:55)

Poster Session

Short Presentation (5/13, 14:55-16:52)

- PA-1 (p.68)** Crystallinity of Double-Layered Polycrystalline Silicon Thin Films Formed by Green Laser Annealing
K. Yamasaki, M. Horita, Y. Sugawara, T. Yamashita, Y. Uraoka
(Nara Institute of Science Technology)
- PA-2 (p.70)** Crystallization of a-Ge and a-Si Film by Soft X-ray Irradiation
N. Isoda¹, T. Inoue², S. Amano², A. Heya¹, K. Kanda², N. Matsuo¹, S. Miyamoto², T. Mochizuki² (¹Department of Material Science and Chemistry, University of Hyogo, ²LASTI, University of Hyogo)
- PA-3 (p.72)** Low-temperature Crystallization of Ge thin films with Ni ferritins
T. Imazawa¹, Y. Tojo¹, M. Uenuma^{1,2}, H. Watanabe^{2,3}, I. Yamashita^{1,2,4}, Y. Uraoka^{1,2} (¹Nara Institute of Science and Technology, ²CREST, ³Osaka University, ⁴Panasonic)
- PA-4 (p.74)** Location Controls of Crystallized Areas in Silicon Films Utilizing Cage Shape Protein
Y. Tojo¹, A. Miura^{1,2}, I. Yamashita^{1,3,4}, Y. Uraoka^{1,4} (¹Nara Institute of Science and Technology, ²National Chiao Tung University, ³Panasonic, ⁴CREST)
- PA-5 (p.76)** Optical Response of Si-Quantum-Dots/NiSi-Nanodots Hybrid Stacked Floating Gate
N. Morisawa, M. Ikeda, S. Nakanishi, A. Kawanami, K. Makihara, S. Miyazaki (Hiroshima University)
- PA-6 (p.78)** Electrical Characteristic in the High Temperatures for Thin-Film Transistor with Very Thin SiNx Film Formed at Source and Drain Region
T. Kobayashi¹, N. Matsuo¹, A. Heya¹, Y. Omura², S. Yokoyama³
(¹University of Hyogo, ²Kansai University, ³Hiroshima University)
- PA-7 (p.80)** Contactless Frequency Domain Lifetime Characterization for Semiconductor Wafers
K. Aoyagi, H. Yoshida (University of Hyogo)

- PA-8 (p.82)** The Influence of N Doping on the Properties of LaAlO Films
M. Honjo, N. Komatsu, C. Kimura, H. Aoki, T. Sugino (Osaka University)
- PA-9 (p.84)** Microscopic Interface Trap Characterization of Gate Stacks with Ultrathin High-K Films by Scanning Capacitance Microscopy
J. Fujieda, S. Kuge, H. Yoshida (University of Hyogo)
- PA-10 (p.86)** Characterization of Interface Traps in Ultrathin Gate Stacks by Contactless C-V Method
A. Hashimoto, K. Aoyagi, H. Yoshida (University of Hyogo)
- PA-11 (p.88)** Evaluation of Turn-on Transient Characteristics of Poly-Si TFT
T. Ota¹, J. Hayashi¹, H. Tsuji^{1,2}, Y. Kamakura¹, K. Taniguchi¹
(¹Osaka University, ²JST-CREST)
- PA-12 (p.90)** Reduction of self-heating effect in silicon MOSFETs on directly bonded Si-on-SiC wafer with high heat conductance
H. Shimizu, R. Araki, H. Shinohara, H. Kinoshita, M. Yoshimoto (Kyoto Institute of Technology)
- PA-13 (p.92)** Effects of Source and Drain Resistance on Drain Conductance Parameter for 20nm MOSFET
Y. Nakade, A. Hiroki, F. Inoue, K. Tomiyama (Kyoto Institute of Technology)
- PA-14 (p.94)** Analysis of CMOS Inverter Delay using λ - V_G MOSFET Model Down to 20nm Era
F. Inoue, A. Hiroki, K. Tomiyama, Y. Nakade (Kyoto Institute of Technology)
- PA-15 (p.96)** Analysis of Static Noise Margin for a 20nm CMOS SRAM Cell
K. Tomiyama, A. Hiroki, F. Inoue, Y. Nakade (Kyoto Institute of Technology)
- PA-16 (p.98)** Performance Evaluation of 1-V Deep Sub-micron Dynamic-Threshold SOI MOSFET
D. Ino, T. Tochio, Y. Omura (Kansai University)

- PA-17 (p.100)** Optimal Design of 2500V Non-punchthrough Type IGBT
E. G. Kang, Y. S. Hong, H. Y. Kang, J. H. Lee, S. B. Go (Far East Univeristy)
- PA-18 (p.102)** Experimental Study for Tank Circuit Control In Super-Regenerative Transponder
A. Itoh, H. Takeuchi, Y. Iida (Kansai Univeristy)
- PA-19 (p.104)** Advanced Low-Power DC-DC Converter Control Circuit for Portable Solar-Cell Battery
N. Hashimoto, Y. Omura (Kansai Univeristy)
- PA-20 (p.106)** Simple and Small Silicon Optical Switch with Silicon Waveguide as an Optical Control Gate
N. Wakama, T. Aki, Y. Iida (Kansai Univeristy)
- PB-1 (p.108)** Numerical Simulation of Electron Motion in Graphene with Vacancies
A. Tam¹, T. Kitayama², N. Mori² (¹UCLA, ²Osaka University)
- PB-2 (p.110)** Influence of electromagnetic field on the real-time electronic dynamics in graphene
K. Saeki, M. Ogawa, S. Souma (Kobe University)
- PB-3 (p.112)** Modulated Phonon Scattering in Graphene Nano-ribbons
T. Kitayama, H. Minari, N. Mori (Osaka Univeristy)
- PB-4 (p.114)** Chemical Bonding Features at TiO₂/Pt Interface and Their Impact on Resistance-Switching Properties
Y. Goto, A. Ohta, H. Murakami, S. Higashi, S. Miyazaki (Hiroshima University)
- PB-5 (p.116)** Optical Absorption Properties of RF-Sputtered β -FeSi₂ Thin Films
N. Kawabata, M. Kawashita, K. Nakamura (Kansai Univeristy)
- PB-6 (p.118)** Effect of molecular vibration on electronic transport through single molecule devices
A. Morihara, M. Ogawa, S. Souma (Kobe University)

- PB-7 (p.120)** RF-Sputtered BST Film Microwave Tunable Device : Comparison between MgO(111) and (100) Substrate
K. Seki¹, P. Lorchirachoonkul¹, T. Yamada², T. Kamo², A. Kimura¹, K. Yamashita¹, H. Funakubo², and M. Noda¹ (¹Kyoto Institute of Technology, ²Tokyo Institute of Technology)
- PB-8 (p.122)** Fabrication and Characterization of Zinc Oxide Thin-Film Transistors at Room Temperature on Glass and Polyethylene Naphthalate Substrates
T. Tachibana, T. Yoshida, T. Maemoto, S. Sasa, M. Inoue (Osaka Institute of Technology)
- PB-9 (p.124)** Electrical Properties of SrTa₂O₆ Thin Films fabricated by Sol-Gel Method
L. Lu¹, T. Nishida¹, K. Uchiyama¹, Y. Uraoka^{1,2} (¹Nara Institute of Science and Technology, ²CREST)
- PB-10(p.126)** A Single-CMOS Oscillator and Potential Application to Alcohol-Detection Sensors
K. Hanajima, S. Tamura, Y. Omura (Kansai University)
- PC-1 (p.128)** Intense THz radiation from InAs epitaxial thin films grown on a GaAs
Y. Ishibasi, S. Umino, K. Takeya*, T. Maemoto, S. Sasa, M. Inoue, M. Tonouchi* (Osaka Institute of Technology, *Osaka University)
- PC-2 (p.130)** Radiation Hardness of Single-Crystalline Zinc Oxide Films Grown by Molecular Beam Epitaxy
T. Amano¹, K. Koike¹, S. Sasa¹, M. Yano¹, S. Gonda, R. Ishigami², K. Kume² (¹Osaka Institute of Technology, ²The Wakasa Wan Energy Research Center)
- PC-3 (p.132)** Alpha Particle Measurements by an InSb Radiation Detector made of Liquid Phase Epitaxially Grown Crystal
Y. Sato, Y. Morita, T. Harai and I. Kanno (Kyoto University)
- PC-4 (p.134)** Micro-fabrication and characterization of an ion-sensitive ZnO-based transistor on a glass substrate

K. Tsuji, K. Koike, K. Ogata, S. Sasa, M. Inoue, M. Yano (Osaka Institute of Technology)

PC-5 (p.136) Ballistic three-terminal devices based on T-branch junctions in InAs/AlGaSb heterostructures

H. Nishioka, T. Maemoto, S. Sasa, M. Inoue (Osaka Institute of Technology)

PC-6 (p.138) Electrical characteristics of AlSiON/AlN/4H-SiC MIS structure at high temperature

N. Komatsu, M. Honjo, C. Kimura, H. Aoki, T. Sugino (Osaka University)

PC-7 (p.140) Monte Carlo simulation of drift and Hall mobilities in n-type GaN

T. Kimizu, K. Kodama and M. Kuzuhara (University of Fukui)

PC-8 (p.142) Reduced current collapse of AlGaN/GaN HFET with Al₂O₃ passivation

N. Yamada, H. Chikaoka, H. Tokuda and M. Kuzuhara (University of Fukui)

PC-9 (p.144) Improved charge-control model for AlGaN/GaN HEMTs

Y. Naito, H. Tokuda and M. Kuzuhara (University of Fukui)

Keynote Speeches (II)

9:20-10:00

- K-3 (p.20)** Future Prospects of Nano-Scale Transistors for VLSI Applications
T. Hiramoto (The University of Tokyo)

Technical Session A (Silicon Devices and Related)

10:00-10:20

- A-1 (p.30)** Study of Electroless Plating for Low Resistance 3D Interconnect
F. Inoue¹, T. Yokoyama¹, H. Miyake¹, S. Tanaka², K. Yamamoto², S. Shingubara¹ (¹Kansai University, ²National Institute of Communication Technology)

10:20-10:40

- A-2 (p.32)** Sub-threshold Characteristics of High-k/Metal Gate MOSFET
T. Imamoto, T. Sasaki, T. Endoh (Tohoku University)

Break (10:40-10:50)

10:50-11:10

- A-3 (p.34)** Dependency of Driving Current on Channel Width in High-k/Metal Gate MOSFET
T. Sasaki, T. Imamoto, T. Endoh (Tohoku University)

11:10-11:30

- A-4 (p.36)** A Liquid-Phase Bonding for High Density Chip-Stack Interconnection
L. Qiu, N. Watanabe*, T. Asano (Kyushu University, *On leave from Fukuoka Industry, Science & Technology Foundation (Fukuoka IST))

11:30-11:50

- A-5 (p.38)** Residual Stress Distribution in a Silicon Chip Encapsulated by

Plastic Packages

N. Ueda, H. Watanabe (RICOH Company, Ltd.)

11:50-12:10

A-6 (p.40) Novel Hybrid Trench Isolated SOI Technology For 50um x 50um RFID Chip

Y. Hirano¹, T. Iwamatsu¹, M. Usami², H. Oda¹, Y. Inoue¹ (¹Renesas Electronics Corp., ²Hitachi, Ltd.)

12:10-12:30

A-7 (p.42) 0.55 V Operation CMOS Voltage Reference Based on the Work Function Difference of Poly Si Gates

H. Watanabe, H. Aota, H. Katoh (Ricoh Co. Ltd.)

Lunch (12:30-13:50)

Technical Session B (Emerging Devices)

13:50-14:10

B-1 (p.46) SWCNT TFT Made from Solution Process via PFOb Solubilizer

X. Yi¹, H. Ozawa², G. Nakagawa¹, T. Fujigaya², N. Nakashima², T. Asano¹ (¹Dept. of Electronics, Kyushu University, ²Dept. of Applied Chemistry, Kyushu University)

14:10-14:30

B-2 (p.48) Bias Voltage Sweep Speed Dependence of Electron Injection in Si-Nano-Dots Floating Gate MOS Capacitor

M. Muraguchi¹, Y. Sakurai², Y. Takada², S. Nomura², K. Shiraishi², M. Ikeda³, K. Makihara³, S. Miyazaki³, Y. Shigeta⁴, T. Endoh¹ (¹Tohoku University, ²University of Tsukuba, ³Hiroshima University, ⁴University of Hyogo)

14:30-14:50

B-3 (p.50) The Micromagnetic Energy Simulation in MRAM Data Retention

K. Kawabata, K. Ishikawa, Y. Inoue, M. Inuishi (Renesas Electronics Corp.)

14:50-15:10

- B-4 (p.52)** Characteristic Evaluation of Thin-Film Transistors using Capacitance-Voltage Characteristics
M. Kimura, T. Nakanishi (Ryukoku University)

15:10-15:30

- B-5 (p.54)** Detection of Biochemical Reaction between Liposome and Denatured Protein by Leakage Current Microsensor
P. Lorchoroonkul¹, T. Shimanouchi², K. Yamashita^{1,2}, H. Umakoshi², R. Kuboi², M. Noda^{1,2} (¹Kyoto Institute of Technology, ²Osaka University)

Break (15:30-15:45)

Technical Session C (Compound Semiconductor Devices)

15:45-16:05

- C-1 (p.58)** Interface State Properties of Al₂O₃/n-GaN Prepared by Atomic Layer Deposition
Y. Hori¹, C. Mizue¹, T. Hashizume^{1,2} (¹Hokkaido University, ²JST-CREST)

16:05-16:25

- C-2 (p.60)** Theoretical Possibilities of InN-Based High Electron Mobility Transistor
A. G. Bhuiyan¹, S. M. Muhtadi², M. T. Hasan², A. Hashimoto¹, A. Yamamoto¹ (¹University of Fukui, ²Khulna University of Engineering & Technology (KUET))

16:25-16:45

- C-3 (p.62)** Demonstration of High Channel Mobility in 4H-SiC MOSFETs by Utilizing Phosphorus-Doped Gate Oxide
D. Okamoto, H. Yano, K. Hirata, S. Kotake, T. Hatayama, T. Fuyuki (Nara Institute of Science and Technology)

16:45-17:05

C-4 (p.64) Highly Reliable ZnO Thin Film Transistor Fabricated by Atomic Layer Deposition
Y. Kawamura, M. Horita, Y. Uraoka (Nara Institute of Science and Technology)

Break (17:05-17:15)

Special Invited Session

17:15-17:45

T-1 (p.24) Current Controllability and Stability of Multi-Mesa-Channel AlGaIn/GaN HEMTs
T. Hashizume^{1,2}, K. Ohi¹ (¹Hokkaido University, ²JST-CREST)

17:45-18:15

T-2 (p.26) Infrared Imaging for Security and Safety
M. Kimata (Ritsumeikan University)

Break (18:15-18:25)

Awards & Closing Remark

18:25-18:35 Award Presentation: Y. Ohmura (Kansai University)

18:35-18:45 Closing Remark: Y. Ohmura (Kansai University)